

# A Prototype of a Non-Invasive Real-Time Beam Size and Energy Spread Monitoring System in an EPICS Environment

Pavel Chevtsov



*May 5-7, 2004 Santa Fe, New Mexico  
Epics Collaboration Meeting*

*Controls Group*

- Introduction
- Synchrotron radiation and its use for beam size and energy spread monitoring
- Synchrotron Light Interferometer (SLI) at Jefferson Lab
- Conclusions



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CEBAF

at

Jefferson Lab



experimental end stations

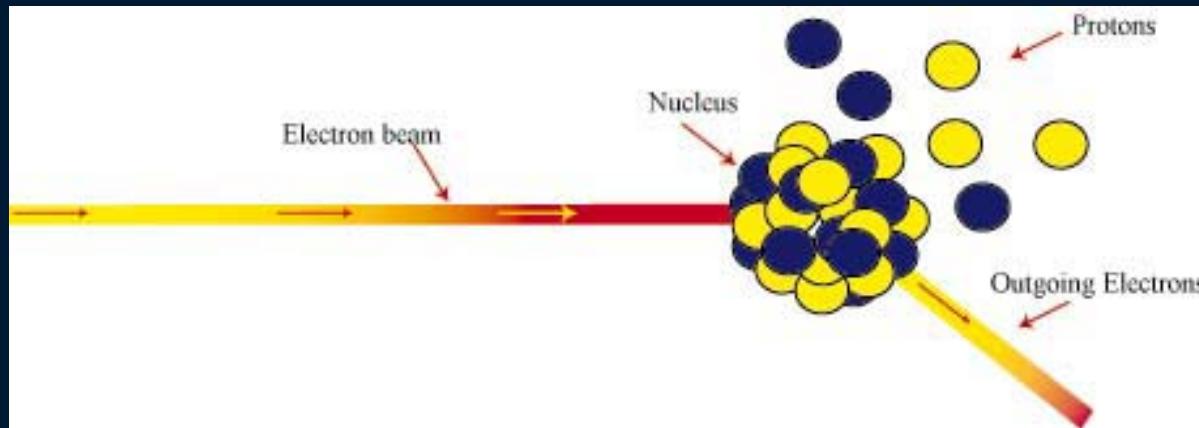


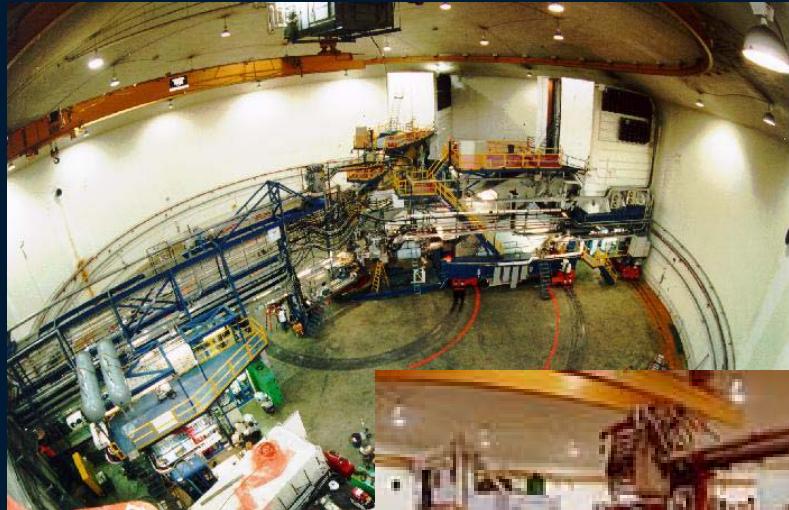
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# high beam quality ???

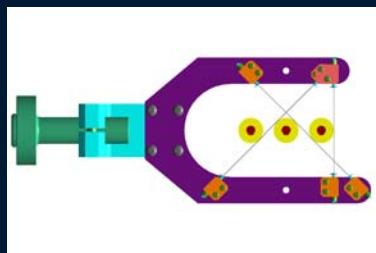
- small beam size ( $\sim 30 \mu\text{m}$  on target)
- very small energy spread ( $\sim 2 * 10^{-5}$ )



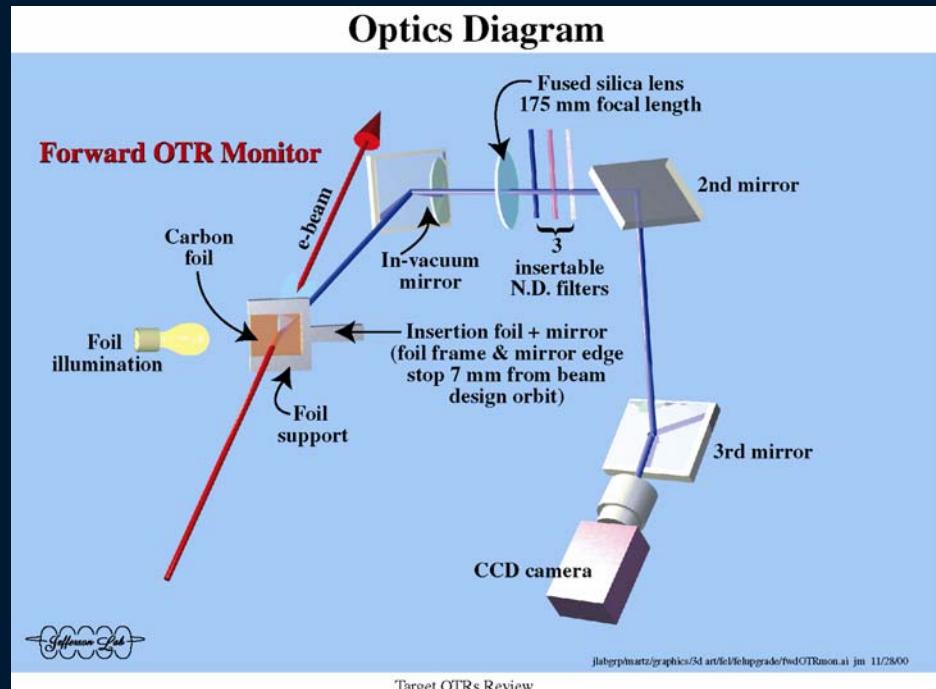


A growing number of experiments at Jefferson Lab require at least 5 GeV, 100  $\mu$ A CW electron beams with continuous (real-time) energy spread monitoring.

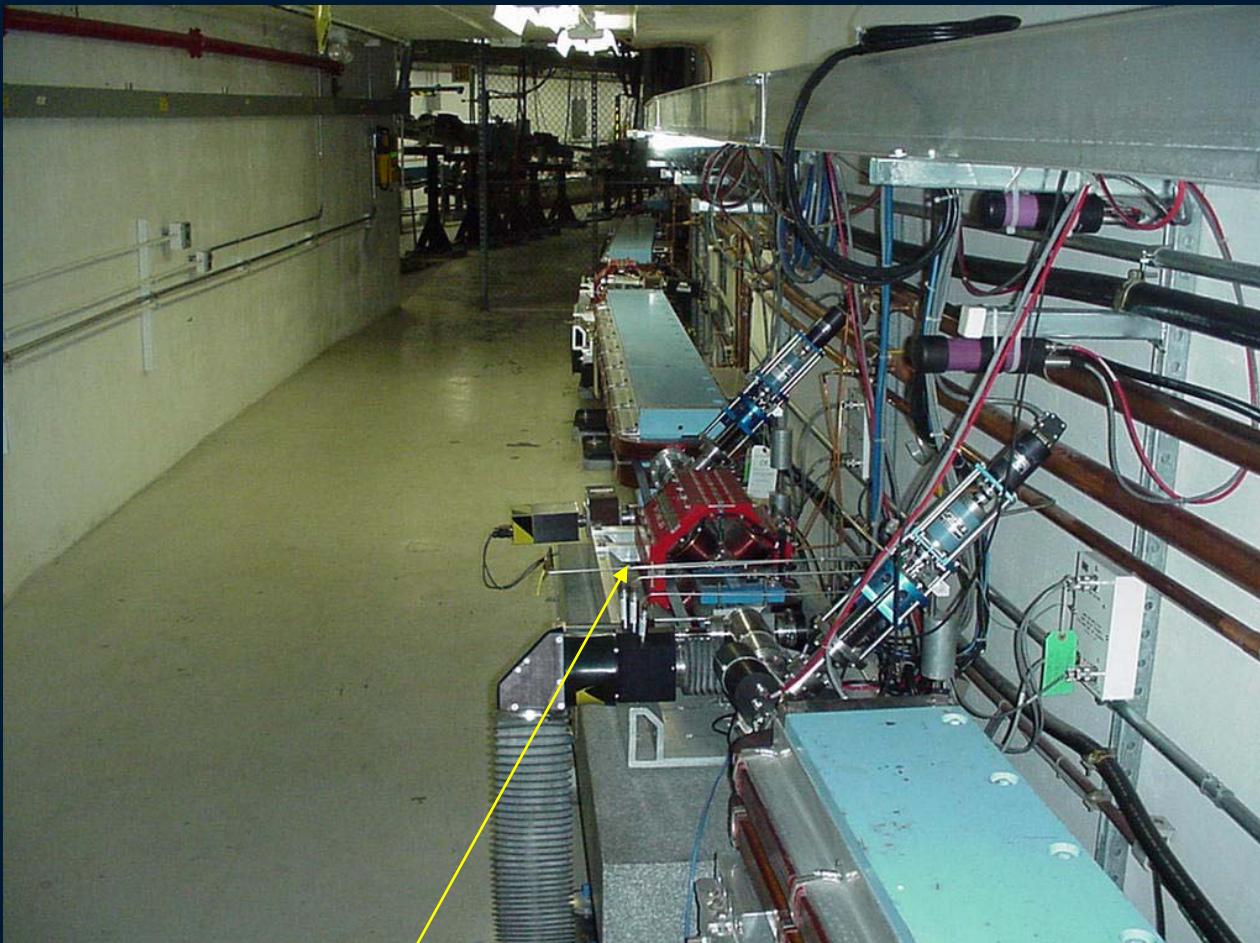
# Beam size and energy spread measurement methods



wire scanners



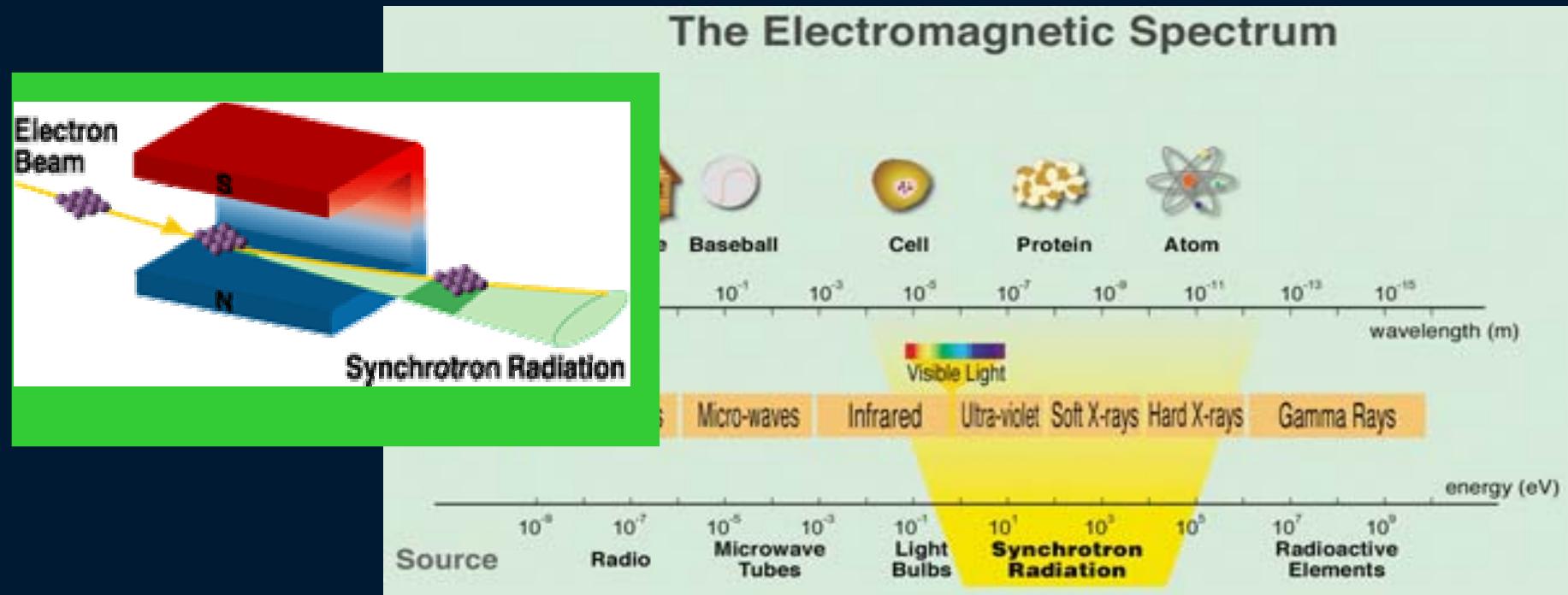
OTR



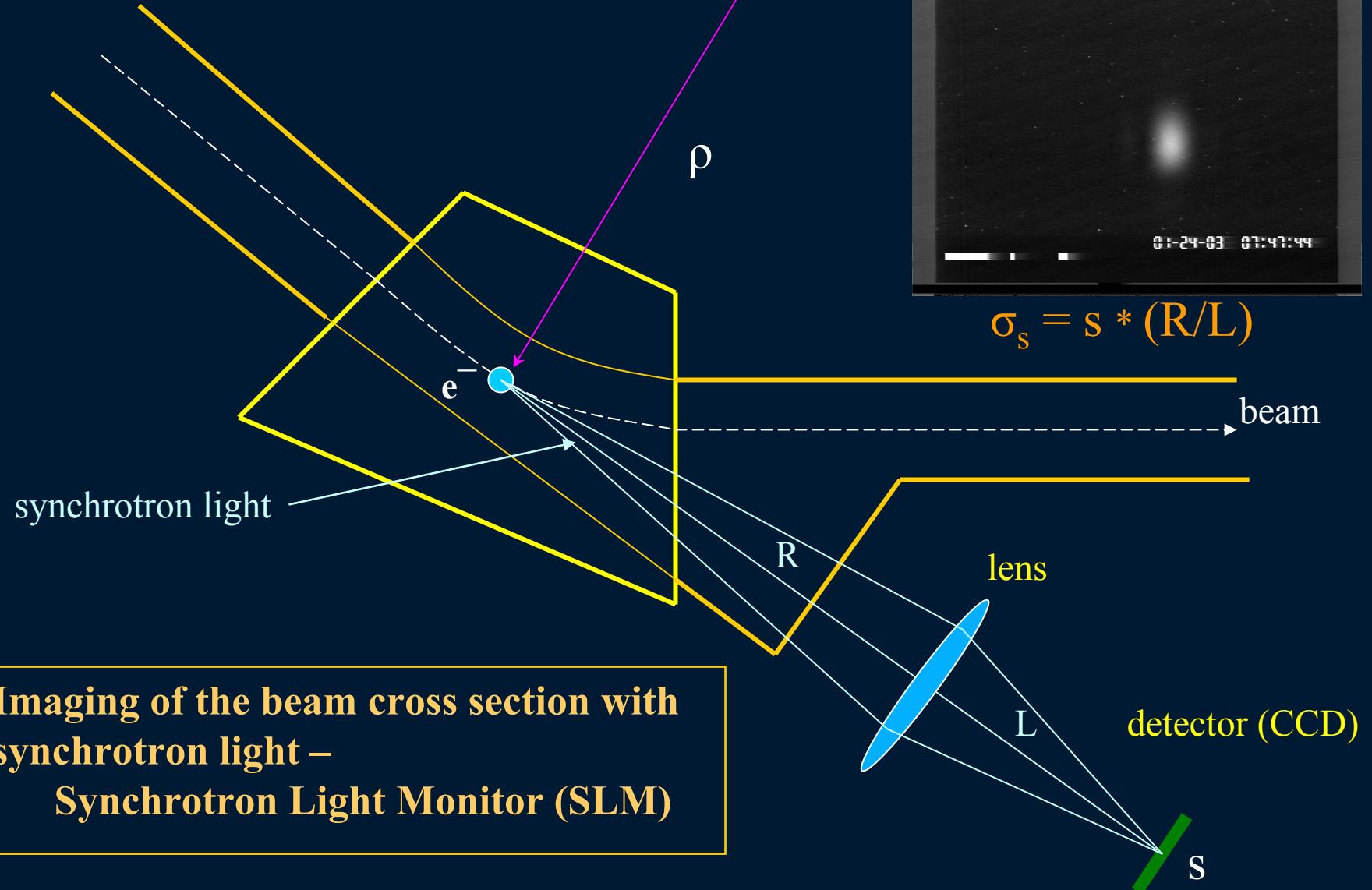
High dispersion location 3C12 ( $\sigma_s < 0.08$  mm)

In high dispersion areas:

- the beam energy spread:  $\sigma_E/E = \sigma_{\text{beam}}/d$
- we can relatively easily use synchrotron light to measure the beam size



# The resolution of SLMs is limited !



The diffraction limited resolution of synchrotron light imaging systems in the visible part of the spectrum [A.Hofmann]:

$$\sigma_S \approx 0.3 (\lambda^2 \rho)^{1/3}$$

Example:

$$\lambda \approx 630 \text{ nm}, \quad \rho \approx 40 \text{ m}$$

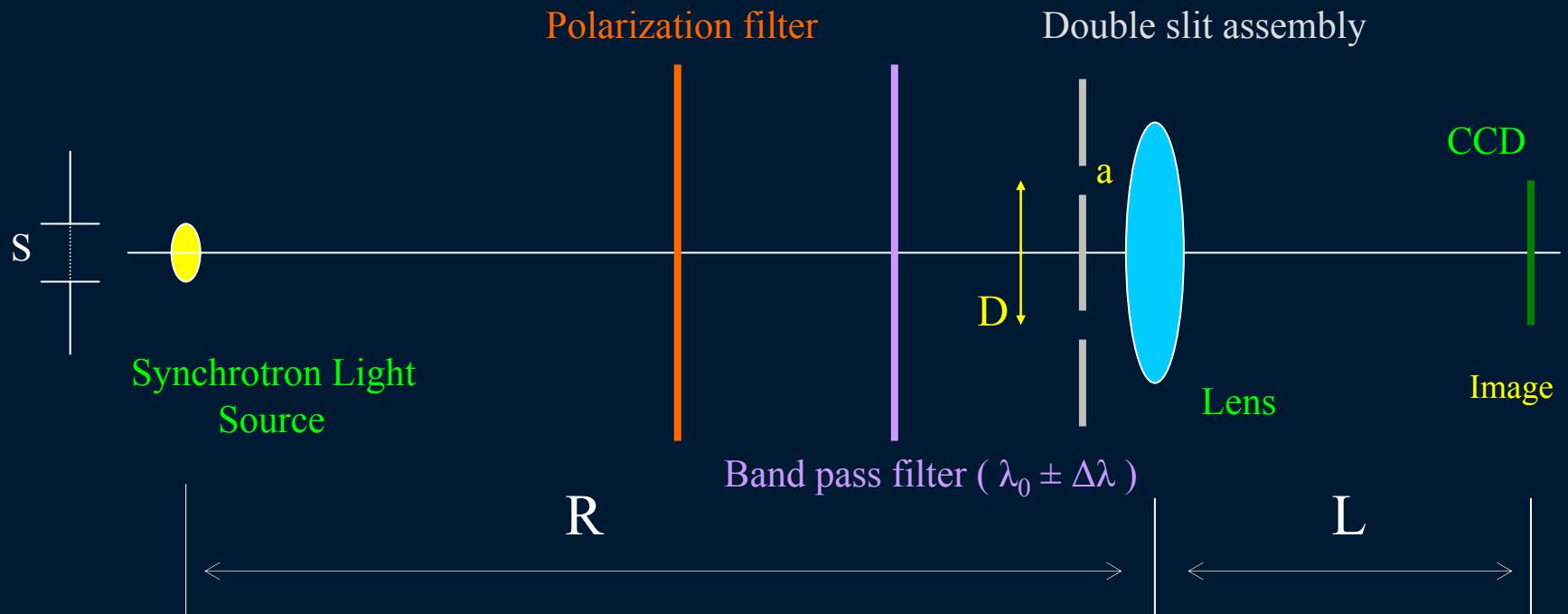
$$\sigma_S \approx 0.08 \text{ mm}$$



# Synchrotron Light Monitor (SLM)



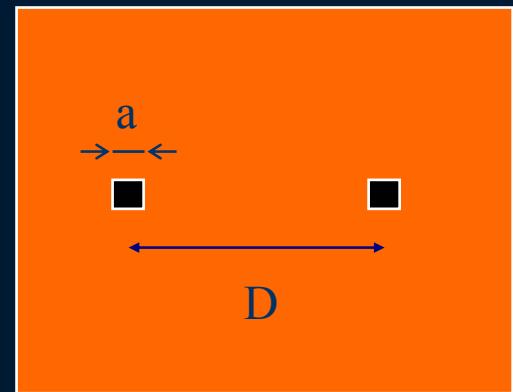
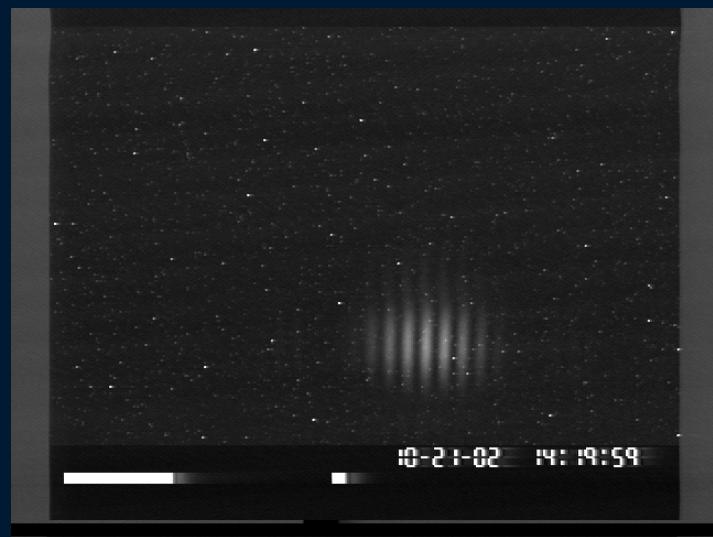
# Synchrotron Light Interferometer (SLI)



SLM beam image

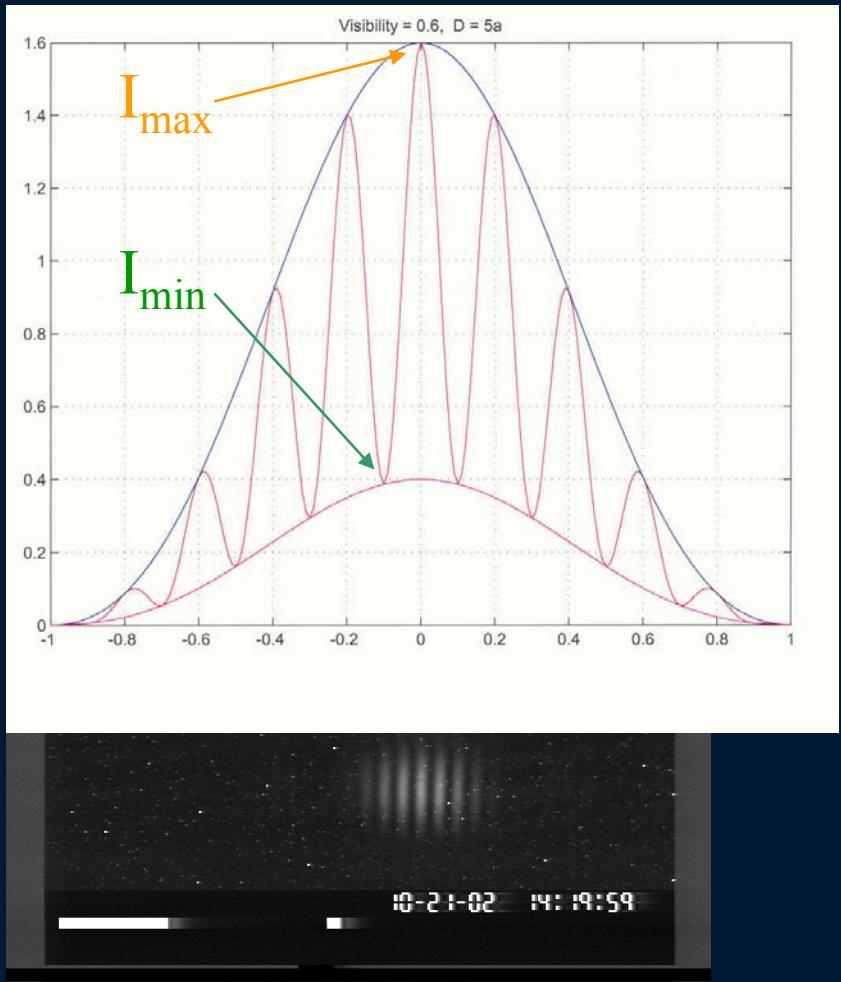


SLI interference picture



$$I(x) = I_0 \left[ \frac{\sin(\alpha x)}{\alpha x} \right]^2 [ 1 + V \cos(kDx/L) ]$$

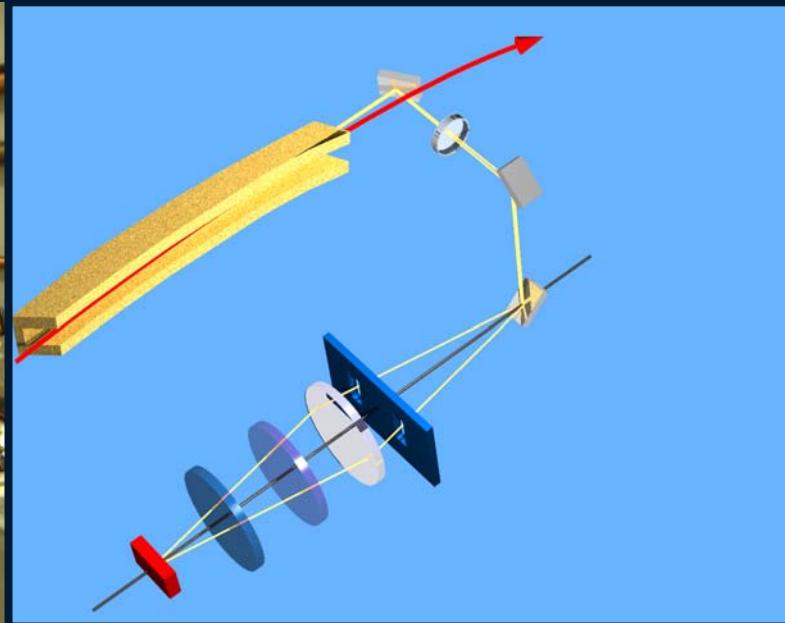
$$\alpha = ka/2L$$



$$V = \frac{I_{\max} - I_{\min}}{I_{\max} + I_{\min}}$$

$$\sigma_{\text{beam}} = \frac{\lambda R}{\pi D} \sqrt{0.5 \ln(1/V)}$$

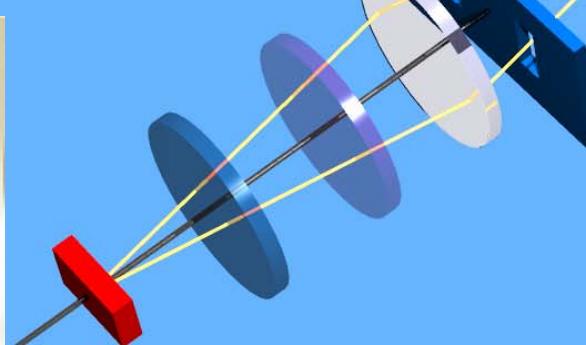
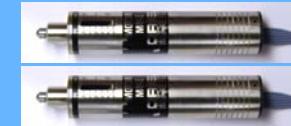
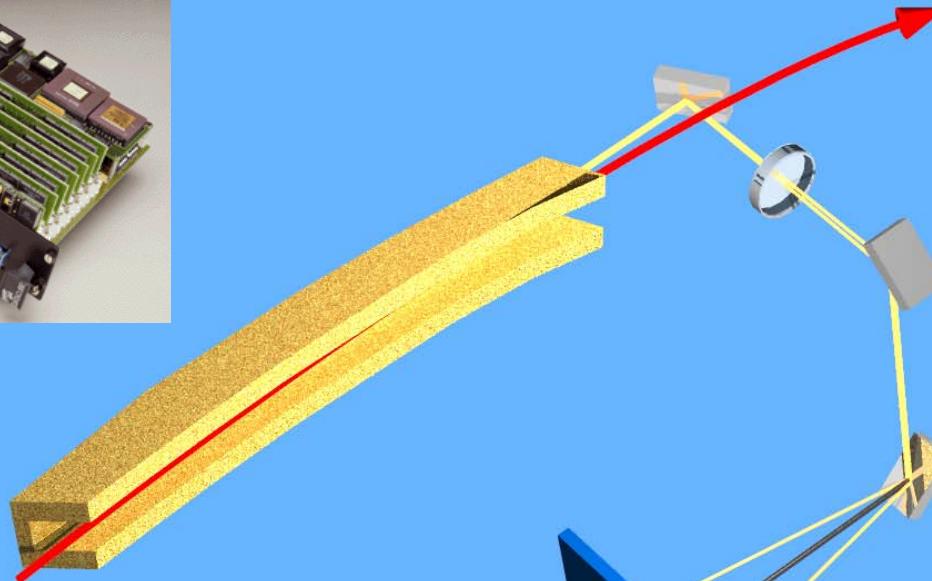
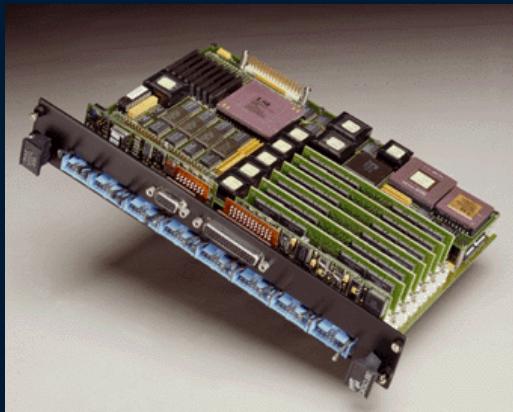
van Cittert, Zernike, Mitsuhashi



Synchrotron Light Interferometer installed at the high dispersion location 1C12



## SLI Control Components



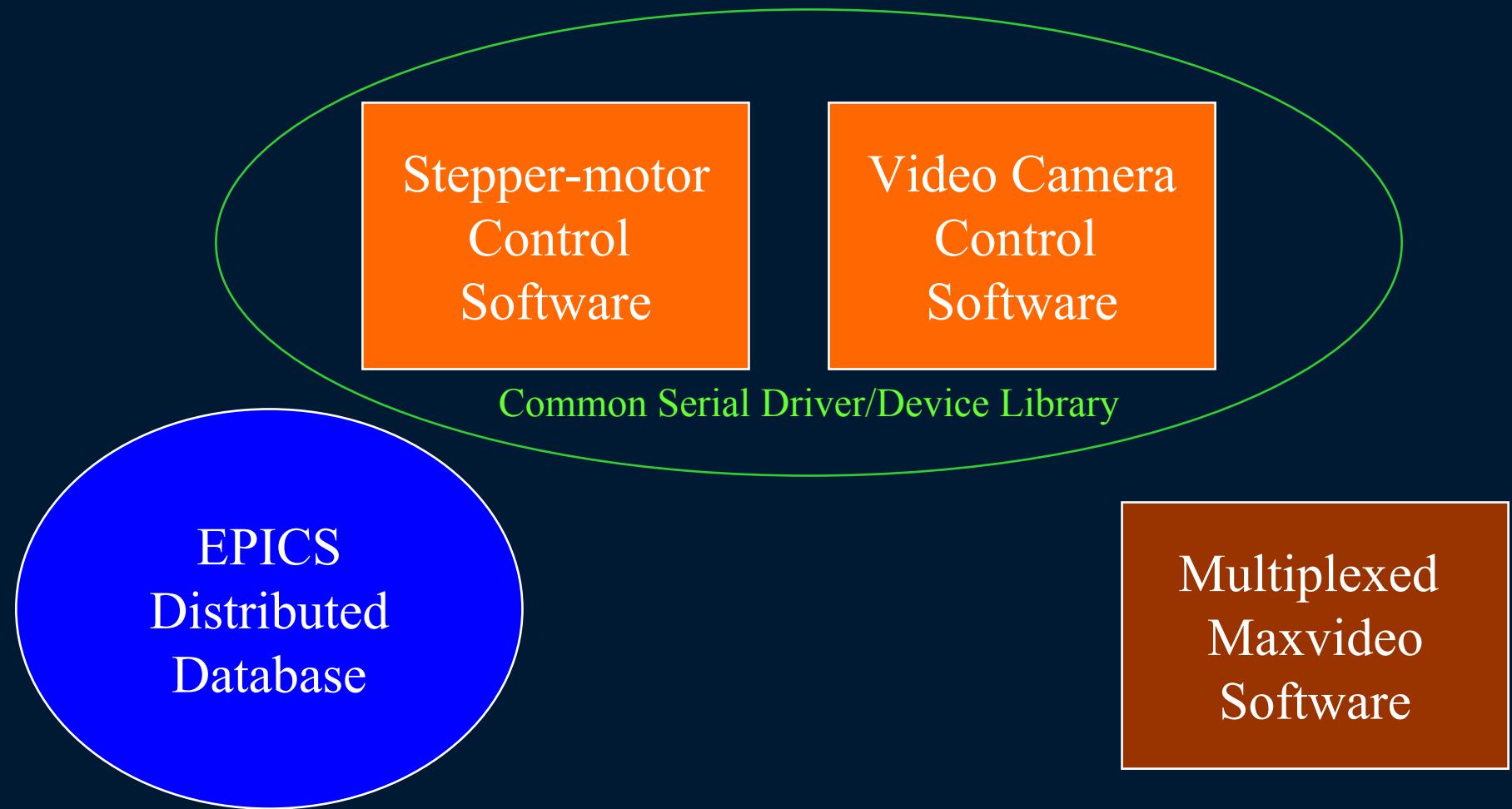
# SLI Control and Image Processing Software



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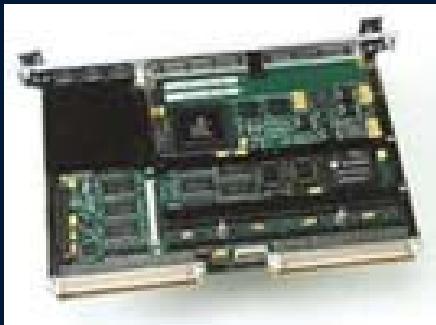
# SLI Control Software



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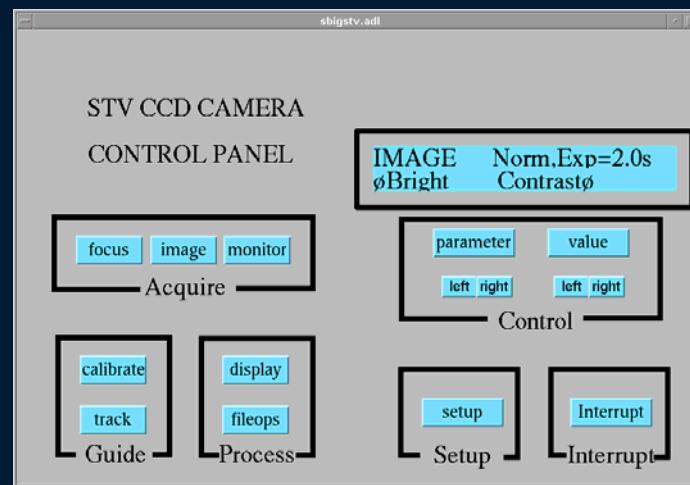
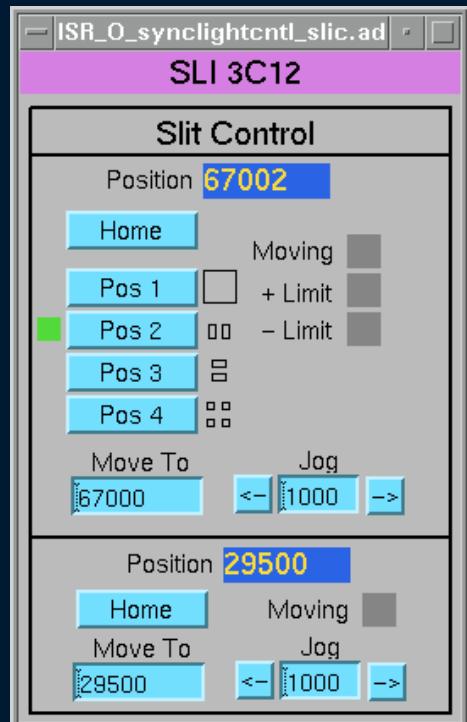
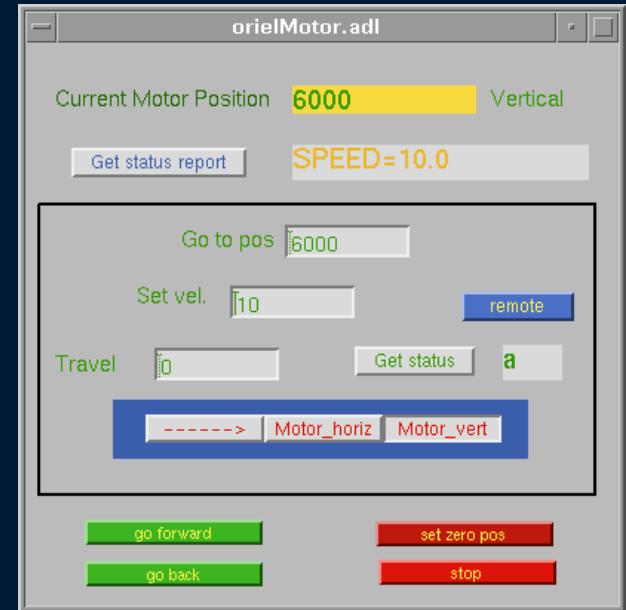
# Stepper-Motor and Video Camera Control Software



Common Serial  
Driver/Device  
Library

Device  
Configuration  
Handler

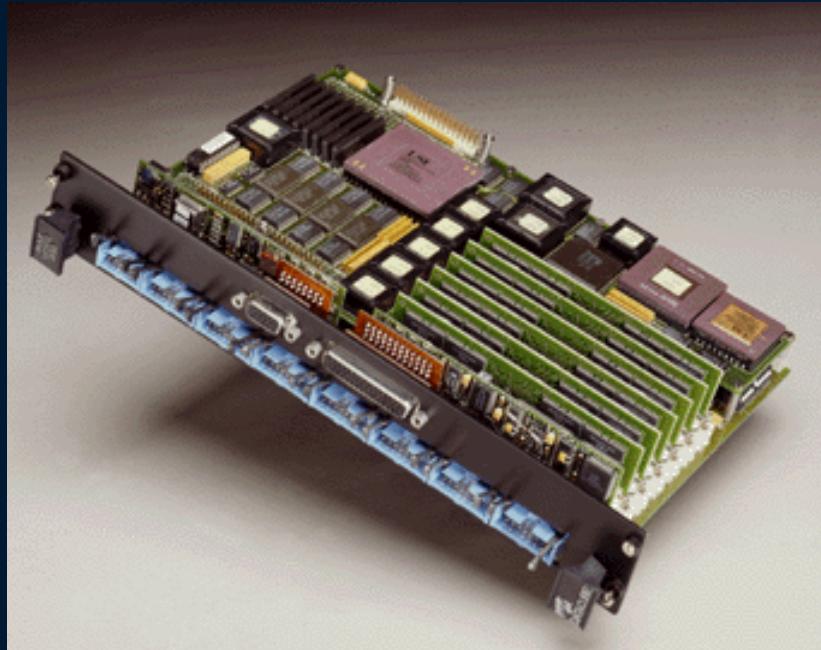




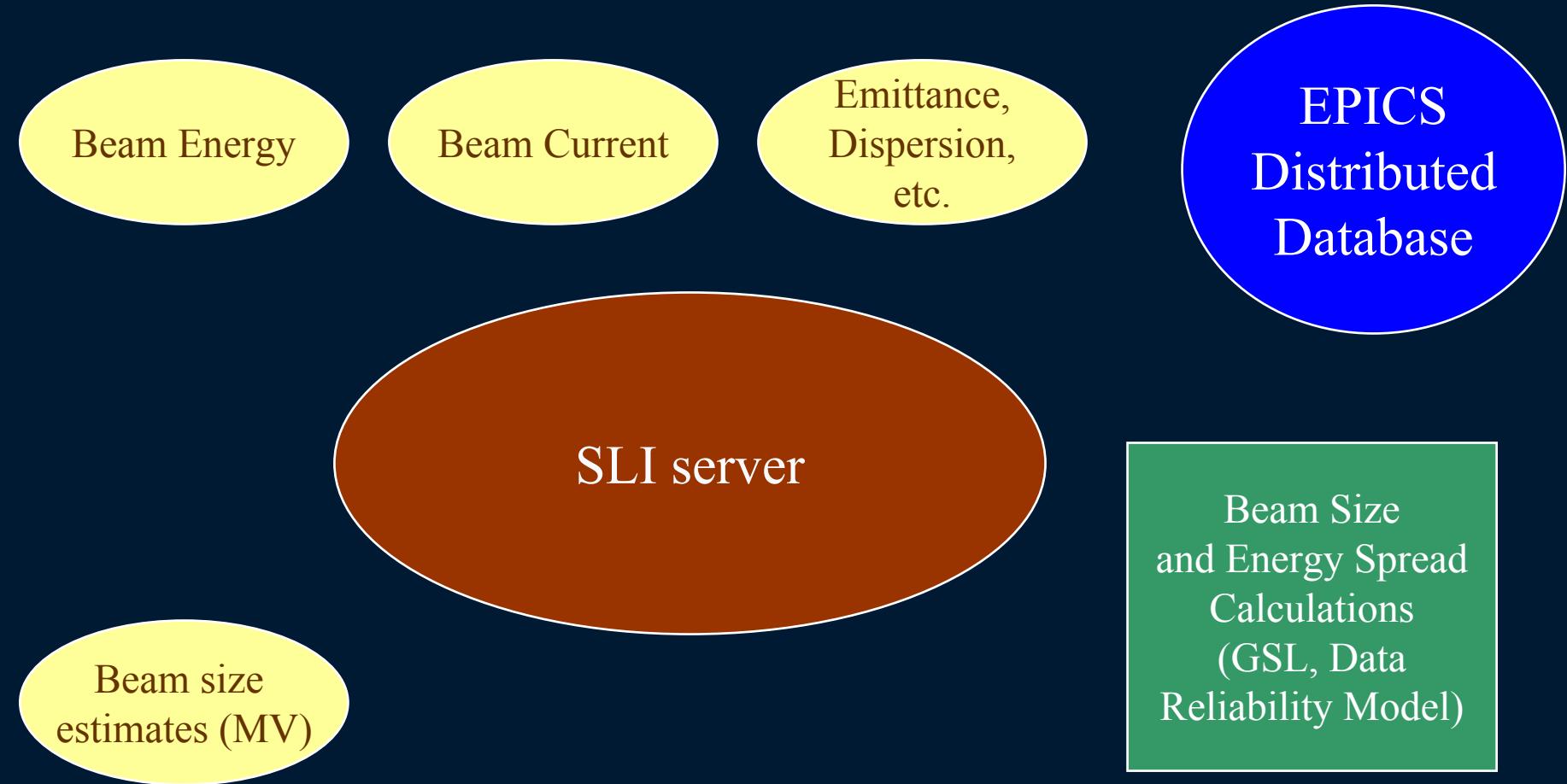
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# Maxvideo (MV, Datacube)



# SLI Image Processing Software



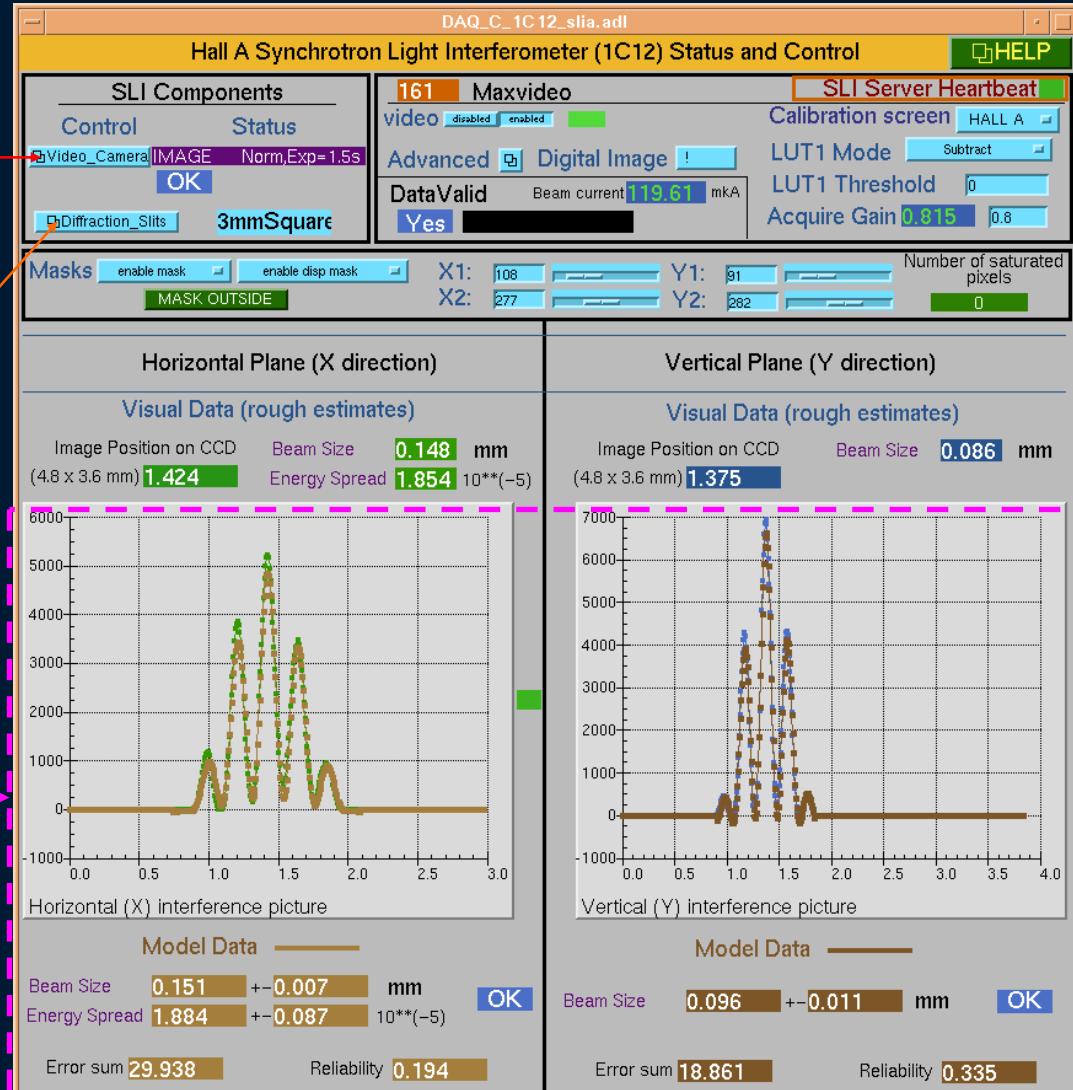
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**SLI server**

## Main SLI Control Screen



## Conclusions:

- We have built a prototype of a real-time non-invasive beam size and energy spread monitoring system (SLI) that has a very high resolution
- We have designed and created control and image processing software in an EPICS environment that can easily be used at all collaboration Institutes



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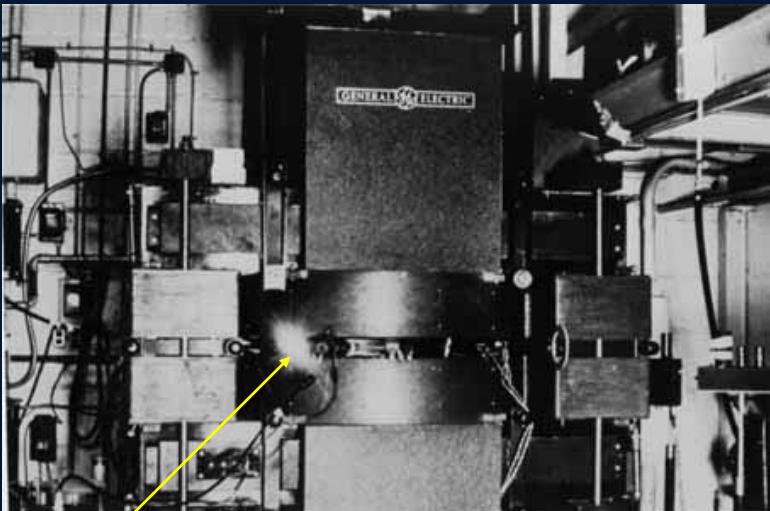
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# Some SLI pictures

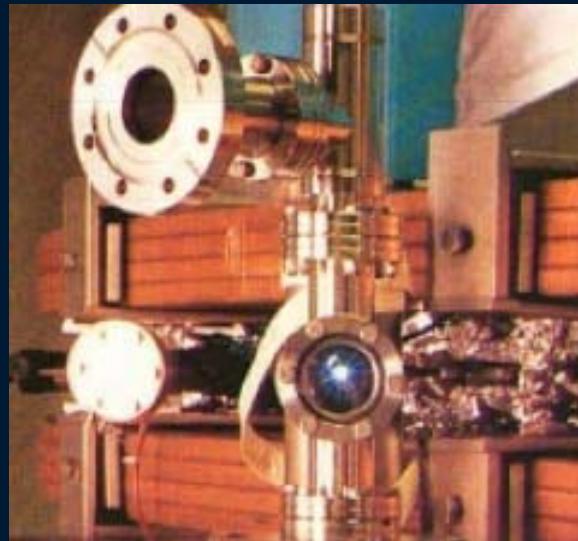


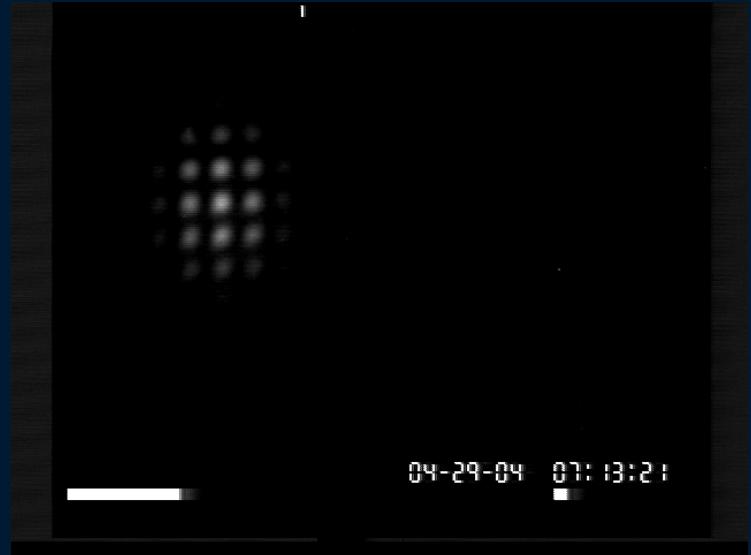
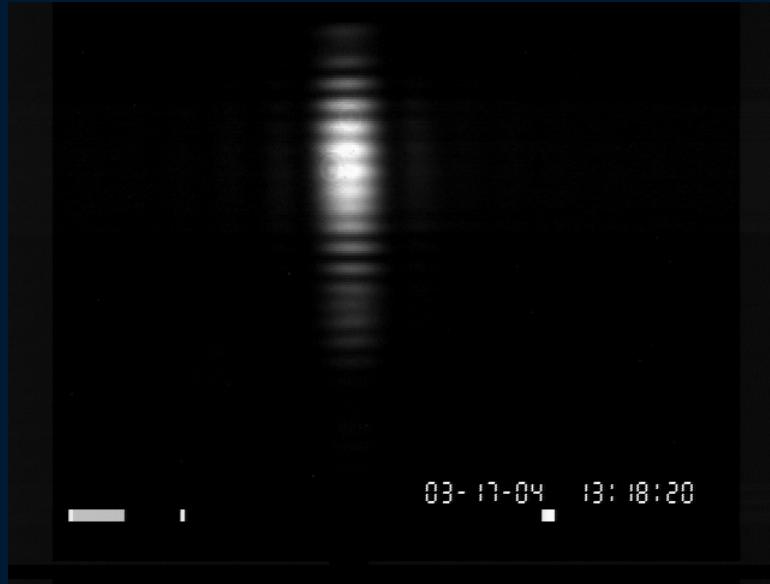
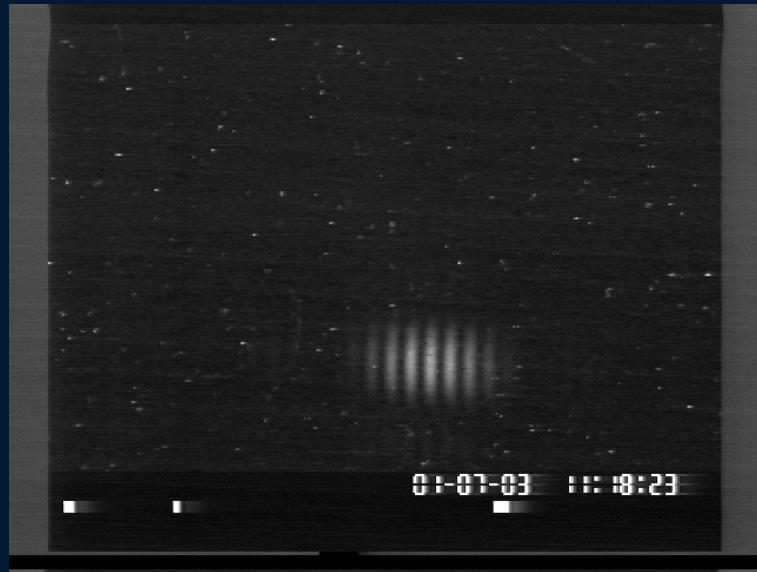
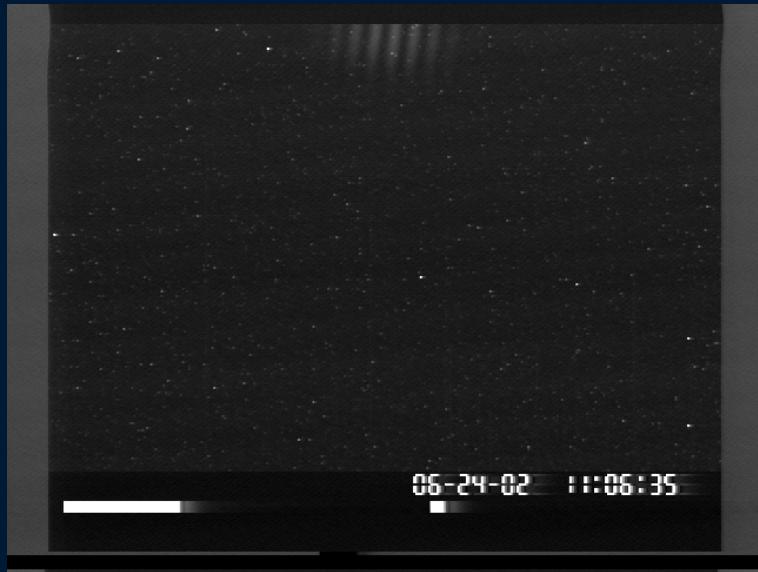
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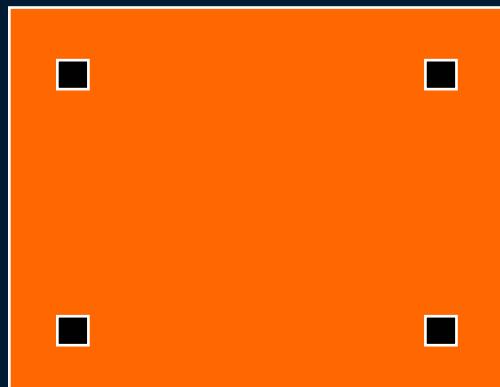
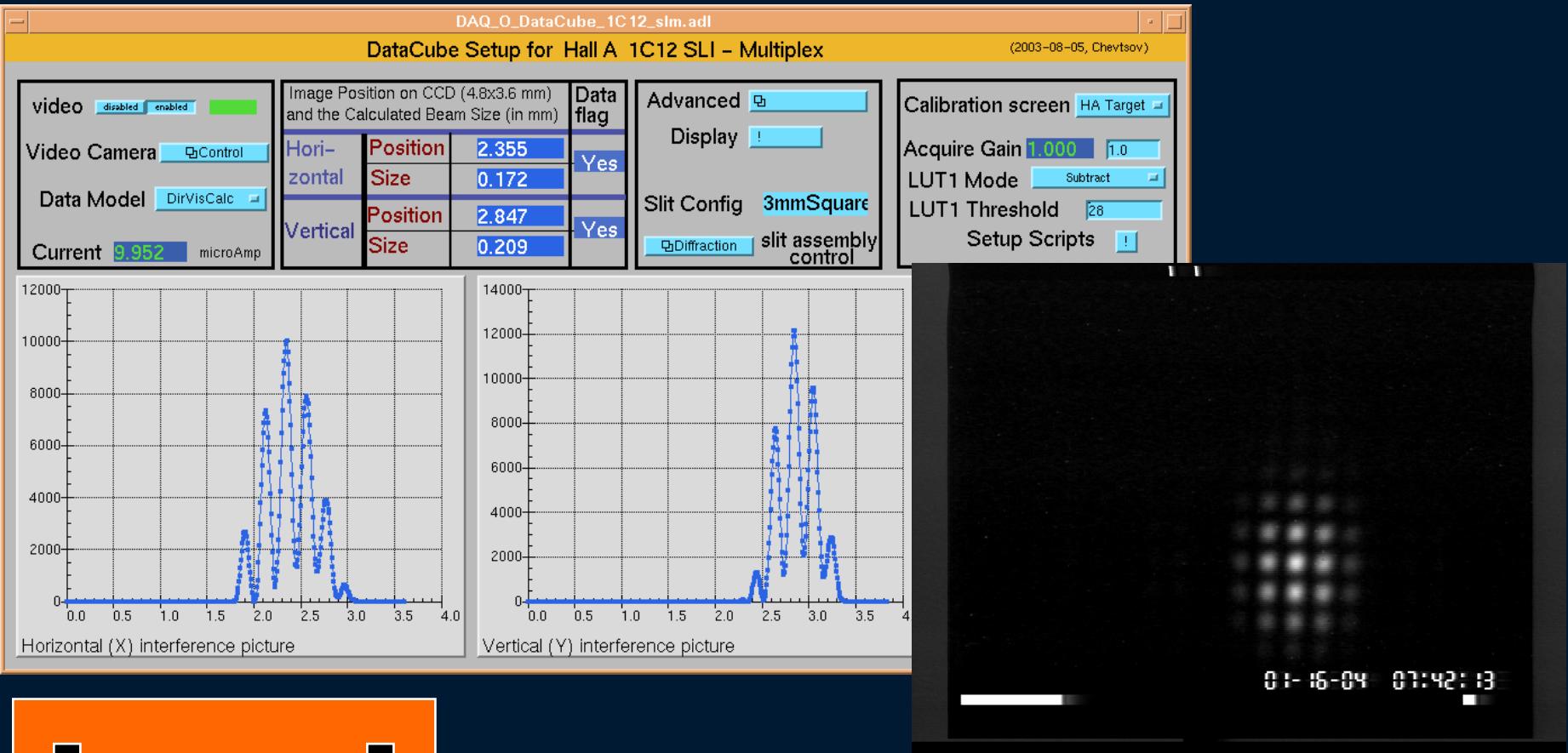
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$$I(x,y) = I(x) \cdot I(y)$$

**E N D**



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